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U.S.S.N. 107789,969

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Mu-Tsang Lin

Group Art Unit: 2125

Serial No.: 10/789,969

Examiner: Carlos R. Ortiz
Rodriguez

Filed: 02/26/2004

In Response to Office Action
Dated: 02/09/2005

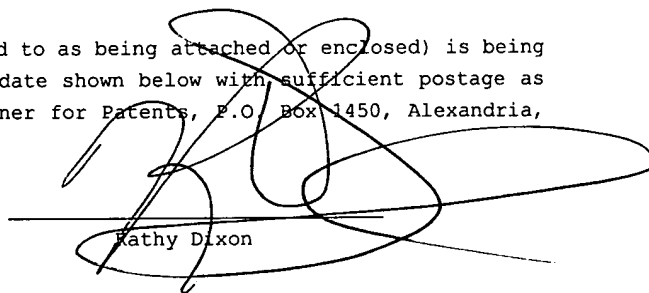
For: TEMPERATURE-SENSING WAFER POSITION DETECTION
SYSTEM AND METHOD

Attorney Docket No.: 67,200-1230

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, Va 22313-1450

Date: Apr. 27, 2005



Kathy Dixon

RESPPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, Va 22313-1450

Dear Sir:

In response to an Office Action mailed 02/09/2005
please enter the following amendments and consider the following
remarks.